

Attorney Docket: 026281-0306769
Client Reference: OPP 031059 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
CHOI

Confirmation Number: 3859

Application No.: **10/735,912**

Group Art Unit: 1763

Filed: December 16, 2003

Examiner: LUND, Jeffrie Robert

Title: **CHEMICAL VAPOR DEPOSITION APPARATUS AND METHOD**

- PROPOSED AMENDMENT UNDER 35 U.S.C. § 1.111 -

Mail Stop Non-Fee Amendments

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed March 28, 2007, the date for responding being June 28, 2007, please amend the above-identified application as follows: